P27195.A01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshiharu FURUKAWA

Group Art Unit: 1756

Serial No: 1

10/711,758

Examiner:

Unassigned

Filed:

October 4, 2004

For:

REDUCED MASK COUNT GATE CONDUCTOR DEFINITION

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria VA 22314

Sir:

Under the provisions of 37 CFR § 1.97 through § 1.99 and pursuant to applicant's duty of disclosure under 37 CFR § 1.56, applicant respectfully brings the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. A copy of the cited documents is enclosed for the convenience of the Examiner.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

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It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

> Respectfully submitted, Toshiharu FURUKAWA

Andrew M. Calderon Reg. No.:38,093

March 31, 2005 GREENBLUM & BERNSTEIN, P.L.C. 1950 Roland Clarke Place Reston, VA 20191 (703) 716-1191 **FORM PTO-1449** 

Patent and Trademark Office

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**Applicant** 

Application No. 10/711,758

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

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Filing Date Group October 4, 2004 1756

## **U.S. PATENT DOCUMENTS FILING DATE EXAMINER** IF **DOCUMENT NUMBER** DATE INITIAL NAME **APPROPRIATE** CLASS SUBCLASS **FOREIGN PATENT DOCUMENTS TRANSLATION CLASS** COUNTRY **SUBCLASS DOCUMENT NUMBER** DATE YES NO OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) M.L. Kerbaugh, et al. "A Method of Sidewall Image Transfer Utilizing the Polymide-Nitride Material Interaction", Research Disclosure, February 1988, Number 286. Anonymous, "Process and Mask Structure for Submicrometer-wide Polysilicon or Polycide Emitters", February 1987. Research Disclosure Database Number: 274061, Research Disclosure Journal Number: 27461 J.E. Cronin, "Method for Making a Single Sidewall Structure", IBM Technical Disclosure Bulletin, Vol. 30, No. 12, May 1988, pp. 157-158. DATE CONSIDERED **EXAMINER**

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation

if not in conformance and not considered. Include copy of this form with next communication to applicant.